

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Gabric, *et al.* Docket No.: INF 2006 VJ 33543 US
Serial No.: 10/586,788 Art Unit: 2893
Filed: September 2, 2008 Examiner: Nikolay K. Yushin
Conf. No.: 1598
For: Plasma Excited Chemical Vapor Deposition Method
Silicon/Oxygen/Nitrogen-Containing-Material and Layered Assembly

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

The following amendments and remarks are presented in response to the Examiner's Office Action mailed June 4, 2009. Please amend the above-referenced application as follows.